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IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re Application of:

Pan et al.

Serial No.: 09/614,113

Filed: July 12, 2000

For: TECHNIQUE FOR ELIMINATION
OF PITTING ON SILICON SUBSTRATE
DURING GATE STACK ETCH

Examiner: C. Brown

Group Art Unit: 1765

Attorney Docket No.: 2915.3US
(96-0149.2)

CERTIFICATE OF MAILING

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Devin R. Jensen
Typed/printed name of person whose signature
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Commissioner for Patents
Washington, D.C. 20231

Dear Sir:

Applicants herein acknowledge the restriction requirement in the above-referenced application. Applicants hereby elect the claims of Group II, claims 3 through 18, without traverse.

Application Serial No. 09/614,113

An early Office Action on the merits is respectfully solicited.

Respectfully submitted,



Devin R. Jensen
Registration No. 44,805
Attorney for Applicants
TRASKBRITT, PC
P. O. Box 2550
Salt Lake City, Utah 84110-2550
Telephone: (801) 532-1922

DRJ/ps:jb
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